

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Attorney Docket Number	4641-65666		
Application Number	10/603,732		
Filing Date	June 24, 2003		
First Named Inventor	Oshino		
Art Unit	<del>1733</del> 2873		
Examiner Name	Not yet assigned MACK		

## **U.S. PATENT DOCUMENTS**

Examiner's Initials*	Clte No. (optional)	Number	Date	Name
Ry		5,986,827	16-Nov-1999	Hale
Rn		5,249;082	28-Sep-1993	Newman
RU		4,726,671	23-Feb-1988	Ahmad et al.
Ry		4,681,408	21-Jul-1987	Ahmad et al.
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## FOREIGN PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Publication Number	Publication Date	Country
RY		08-68899	12-Mar-1996	Japan
Ry		EP 1 312 965 A1	21-May-2003	Europe

Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS
RM		"Construction of the Projection Optics Box for the Engineering Test Stand", presentation to International SEMATECH, by John S. Taylor, October 2000, 24 pages.
RM		"Fabrication of ETS Set II Optics: Results and Future Development", presentation to 2 <sup>nd</sup> International Workshop on EUV Lithography, by Lou Marchetti et al., October 2000, 20 pages
Ry		"High-NA Camera for an EUVL Microstepper", presentation by Layton Hale et al., October 2000, 13 pages.

EXAMINER SIGNATURE:	Xint ?	Mari	DATE CONSIDERED:	9/29/04
	1 X W Y 4	2000		10101

<sup>\*</sup> Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.